



RCE/1765 \$
PATENT #21

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Julia S. SVIRCHEVSKI et al.

Application No. 09/336,401

Filed: June 18, 1999

For: POST-PLASMA PROCESSING
WAFER CLEANING
METHOD AND SYSTEM

) Attorney Docket No. LAM1P109

) Examiner: L. Umez-Eronini

) Group Art Unit: 1765

) Date: June 30, 2003

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on June 30, 2003.

Signed:

Peter B. Martine

REQUEST FOR CONTINUED EXAMINATION (RCE)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is a Request for Continued Examination (RCE) under 37 C.F.R. § 1.114 of the above-identified patent application. Applicants request that the arguments set forth in the attached Amendment be considered and submit that this paper satisfies the submission requirement set forth in 37 C.F.R. § 1.114.

Applicants are attaching a check in the amount of \$1,680.00 to cover the RCE fee of \$750.00 set forth in 37 C.F.R. § 1.17(e) and the three-month extension of time fee of \$930.00 required under 37 C.F.R. §§ 1.136 and 1.17. Regarding the extension of time fee, Applicants filed a Notice of Appeal on January 28, 2003 and, consequently, an Appeal Brief was due on March 28, 2003. As June 28, 2003 fell on a Saturday, a three-month extension of time is needed to enable the filing of this RCE.

In the event additional fees are due to enable the filing of this RCE, the Commissioner (or the Director) is authorized to charge such fees to Deposit Account No. 50-0805 (Order No. LAM1P109).

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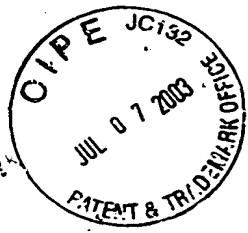
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02 FC:1253

750.00 OP
930.00 OP

Respectfully submitted,
MARTINE & PENILLA, LLP

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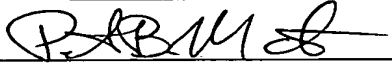
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Peter B. Martine

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicants submit this paper in conjunction with the Request for Continued Examination (RCE) being submitted concurrently submitted herewith. Please amend this application as follows:

The **Amendments to the Claims** made herein are reflected in the **Listing of Claims**, which begins on page 2 of this paper.

Applicants' **Remarks** begin on page 6 of this paper.